

Title (en)  
MICROMECHANICAL COMPONENT WITH REAR VOLUME

Title (de)  
MIKROMECHANISCHES BAUELEMENT MIT RÜCKVOLUMEN

Title (fr)  
COMPOSANT MICROMÉCANIQUE AVEC VOLUME POSTÉRIEUR

Publication  
**EP 2308243 A1 20110413 (DE)**

Application  
**EP 09779612 A 20090603**

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Abstract (en)  
[origin: WO2010009934A1] The invention relates to a micromechanical component or a method for manufacturing such a component, wherein a cavity (270) is produced in the substrate starting from an opening (215) at the rear of a monocrystal semiconductor substrate (200). The process used for this purpose is controlled in connection with the monocrystal semiconductor substrate used such that a largely rectangular cavity is formed.

IPC 8 full level  
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